

Please amend the specification as follows:

On page 12, please replace the paragraph as follows:

—Turning now to Fig. 4B, a second embodiment of a fabrication apparatus is shown. In this embodiment, a chuck 500 is positioned inside a chamber. The chuck 500 supports a wafer 502. The chamber has vacuum bellows 510. The chuck 500 is driven by a wafer rotator 520 which rotates the wafer 502 and the chuck 500 in a pendulum-like manner. The chuck 500 is also powered by a linear motor 530 to provide up/down motion. A plurality of sources ~~540-544~~  
540, 542 and 544 perform deposition of materials on the wafer 502.--